

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Suzuki, et al.

Serial No.: 10/004,489

Confirmation No.: 9428

Filed: October 23, 2001

For: Method of Forming Film,
Method of Manufacturing
Semiconductor Device and
Film Forming Apparatus

MAIL STOP 313(c)
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 2818

Examiner: Renee R. Berry

FAX RECEIVED

FEB 10 2005

OFFICE OF PETITIONS

**CERTIFICATE OF FACSIMILE
TRANSMISSION UNDER 37 CFR 1.8**

EXPRESS ABANDONMENT AFTER PAYMENT OF ISSUE FEE

Applicants hereby request that the referenced application be expressly abandoned.

Respectfully submitted,

Thurston 200

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